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Serial No.: 10/706,061

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Docket No.: FIS920030240

Kangguo Cheng, et al.

Serial No.: 10/706,061

Group Art Unit: 2812

Filed: November 13, 2003

Examiner: Issac, Stanetta D.

For: **STRAINED SILICON ON A SiGe ON SOI SUBSTRATE**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

In response to the Restriction Requirement dated September 3, 2004, Applicants elect claims 1-24, without traverse.

Applicants believe that no extensions of time or fees for net addition of claims are required at this time. However, if additional extensions of time are necessary to prevent abandonment of this application, then such extensions of time are hereby petitioned under 37 C.F.R. §1.136(a), and any fees required therefor (including fees for net addition of claims) are hereby authorized to be charged to International Business Machines Corporation's deposit Account No. 09-0458.